Notice of References Cited

The state of the s

Application/Control No.

O9/950,038

Examiner

Martin J Angebranndt

Applicant(s)/Patent Under
Reexamination
ZAIT ET AL.

Page 1 of 2

U.S. PATENT DOCUMENTS

*		Document Number Country Code-Number-Kind Code	Date MM-YYYY	Name	Classification
	Α	US-6333485	12-2001	Haight et al.	219/121.68
	В	US-5463200	10-1995	James et al.	219/121.68
	С	US-4190759	02-1980	Hongo et al.	219/121M
	D	US-3889272	06-1975	Lou et al.	346/135
	Е	US-4727234	02-1988	Oprysko et al.	219/121L
	F	US-6190836	02-2001	Grenon et al.	430/311
	G	US-6346352	02-2002	Hayden et al.	430/5
	Н	US-5208818	05-1993	Gelbart et al.	372/30
	1	US-5830606	11-1998	Okamoto	430/5
	J	US-5395718	03-1995	Jensen et al.	430/5
	К	US-4923772	05-1990	Kirch et al.	430/5
	L	US-4529991	07-1985	Wada et al.	346/76L
	М	US-			

FOREIGN PATENT DOCUMENTS

*	:	Document Number Country Code-Number-Kind Code	Date MM-YYYY	Country	Name	Classification
	N					
	0					
	Р					
	Q					
	R					
	s					
	Т					

NON-PATENT DOCUMENTS

*		Include as applicable: Author, Title Date, Publisher, Edition or Volume, Pertinent Pages)
	U	Ihleman et al. "Excimer laser ablation patterning of dielectric layers", Applied Surf. Sci., Vol. 86(1-4) pp. 228-233 (abstract only)
	٧	Haight et al., "Implementation and performance of a femtosecond laser mask repair system in manufacturing", Proc. SPIE vol. 3546, pp. 477-484
	w	Shani et al., "high resolution near field mask repair with femtosecond laser
	х	O'Connor et al. "Next generation laser based mask repair tool", Proc. SPIE vol. 1604 pp. 167-178 (1991)

*A copy of this reference is not being furnished with this Office action. (See MPEP § 707.05(a).) Dates in MM-YYYY format are publication dates. Classifications may be US or foreign.

Application/Control No. O9/950,038 Applicant(s)/Patent Under Reexamination ZAIT ET AL. Examiner Martin J Angebranndt Art Unit Page 2 of 2

U.S. PATENT DOCUMENTS

	U.S. FATENT DOCUMENTS				
*		Document Number Country Code-Number-Kind Code	Date MM-YYYY	Name	Classification
	Α	US-			
	В	US-			
	С	US-			
	D	US-			
	Е	US-			
	F	US-			
	G	US-			
	н	US-			
	1	US-			
	J	US-			
	К	US-			
	L	US-			
	М	US-			

FOREIGN PATENT DOCUMENTS

*		Document Number Country Code-Number-Kind Code	Date MM-YYYY	Country	Name	Classification
	N					
	0					
	Р					
	Q					
	R	,				
	S					
	Т					

NON-PATENT DOCUMENTS

*		Include as applicable: Author, Title Date, Publisher, Edition or Volume, Pertinent Pages)				
	U	Haight et al., "MARS:Femtosecond laser mask advanced repair system in manufacturing", J Vac. Sci. Technol. B 17(6) pp 3137-3143 (Nov/Dec 1999)				
	٧					
	w					
	х					

*A copy of this reference is not being furnished with this Office action. (See MPEP § 707.05(a).)

Dates in MM-YYYY format are publication dates. Classifications may be US or foreign.